



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Filed: January 31, 2002
Serial No.: 10/059,321
Title: Reduction of Negative Bias Temperature Instability in Narrow Width PMOS Using F2 Implantation

Docket No.: 2001 P 14585 US
Examiner: Stanetta D. Isaac
Art Unit: 2812

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicant wishes to bring to the attention of the U.S. Patent and Trademark Office the information noted on the enclosed PTO Form 1449 which may be considered material to the examination of the above identified application.

No fees are due at this time as this Information Disclosure Statement is being filed concurrently with a Request for Continued Examination. In the event that there are any fees due, please charge the same, or credit any overpayment, to Deposit Account No. 50-1065. A copy of a search report from a related foreign application is provided for the Examiner's convenience.

Respectfully submitted,

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